

Notice of References Cited	Application/Control No. 10/604,565		Applicant(s)/Patent Under Reexamination CHENG ET AL.	
	Examiner Thao P. Le		Art Unit 2818	Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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*	B	US-2004/0079979	04-2004	Lee et al.	257/301
*	C	US-6,740,555	05-2004	Tews et al.	438/242
*	D	US-5,395,786	03-1995	Hsu et al.	438/248
*	E	US-6,699,794	03-2004	Flietner et al.	438/700
	F	US-2002/0105019	08-2002	Mandelman et al.	257/296
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	M	US-			

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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
*	U	S. Wolf and R.N. Tauber, Silicon Processing for the VLSI Era, Vol. 1, Lattice Press, California, pp. 307-308, 323-324
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.